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SERIAL NO. 09/899,383

APPLICANT:

Scott A. Chalmers, et al.

FILING DATE: July 3, 2001

GROUP: 2877

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	A TRADE NO DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
148	4,555,767	11/26/85	Case et al.	364	563	10/28/92
HP	5,436,725	7/25/95	Ledger	356	357	10/12/93
1+8	5,747,813	05/05/98	Norton et al.	250	372	04/14/94

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB Class	TRANS YES	LATION NO
H8	EP 0 644 399 A2	03/22/95	Europe (Dainippon Screen Mfg. Co. Ltd.)				
100	EP 0 652 415 A1	05/10/95	European				
WP	EP 0 663 265 A1	07/19/95	Europe (International Business Machines Corporation)				

	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)					
H8	AD	Jones, G.R. et al., Chromatic Interferometry for an Intelligent Plasma Processing System, MEASUREMENT SCIENCE & TECHNOLOGY, Vol. 5, No. 6, June 1994 (1994-06), Pages 639-647, XP 000456344; Bristol, GB.				
WP	AE	Lange, V. et al., Reflexionsinterferometrie zur Kontrolle dünner Silizium-Membranen, TECHNISCHES MESSEN, Vol. 61, No. 9, September, 1994 (1994-09), pages 346-351, XP000465894, pages 346-351, figures 1-4				
	AF	ImSpector Imaging Spectrograph brochure including specifications, Spectral Imaging Ltd., Oulu, Finland, (3 pages)				
	AG	CCD Detectors, Optical Systems Division, retrieved on-line 6/21/00, (3 pages)				
	AH	Advanced Thin Film Measurements – About thin Film, Filmetrics, retrieved on-line 6/21/00; pages 1-6				
	AI	Advanced Thin Film Measurements – Operation, Filmetrics, retrieved on-line 6/21/00; pages 1-2				
• , ,	AJ	Advanced Thin Film Measurements – PTFEON Data, Filmetrics, retrieved on-line 6/21/00; (1 page)				
138	AK	Advanced Thin Film Measurements – faq, Filmetrics, retrieved on-line 6/21/00; (2 pages)				

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EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant